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Feng Wu Niang

Name

Wu - Niang Feng

Signature

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant Wu-Niang Art Unit: 1764
Feng
Series No 09/944,947 Examiner: DUONG, THANH P
Filed 09-01-2001
Title Semiconductor waste-gas treating apparatus
being filth sedimentation-and
etching-proof

Mail Stop Non-Fee Amendment

Honorable Assistant Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

Responsive to the Official Action date 06 / 28 / 2003, please amend the above-referenced Patent Application as following:

AMENDMENT